



## **CyberOptics Discusses High-Precision Relative Humidity Measurement Method at the European Mask and Lithography Conference**

**Minneapolis, Minnesota** — June 13, 2016 — [CyberOptics® Corporation](#) (NASDAQ: CYBE), a leading global developer and manufacturer of high precision 3D sensing technology solutions, will lead a poster session during the Technical Exhibition at the 32<sup>nd</sup> [European Mask and Lithography Conference](#) (EMLC) in Dresden, Germany, June 21-22.

The conference brings together scientists, researchers, engineers and technologists from around the world to present innovations at the forefront of mask and wafer lithography. CyberOptics' Allyn Jackson, Field Applications Engineer and Director of Sales for U.S. and Europe, will discuss effective ways to monitor relative humidity (RH) in immersion scanner reticle environments to reduce a phenomenon called "haze."

"Current RH measurement methods have a number of drawbacks. For example, hand-held RH sensors are inconvenient and they can compromise the reticle environment if the scanner panels are opened. It might take hours to requalify the tool before going back on-line. Also, many areas are inaccessible by hand-held RH sensors, in-situ RH sensors or benchtop type RH sensors," said Jackson. "By contrast, equipment qualifications can be done faster and more effectively using a high-precision, wireless sensor to measure and monitor RH to reduce reticle haze."

Solutions reviewed in the case study will include CyberOptics's ReticleSense® Auto Multi Sensor that can travel throughout the entire reticle environment to wirelessly capture RH measurements. The device can also measure vibration and leveling – all in real-time to improve yields and tool uptime.

### **About the WaferSense and ReticleSense Line**

The WaferSense measurement portfolio including the Auto Leveling System (ALS), the Auto Gapping System (AGS), the Auto Vibration System (AVS), the Auto Teaching System (ATS), the Airborne Particle Sensor (APS), the next-generation Airborne Particle Sensor (APS2) and the new Auto Multi Sensor (AMS) are available in various wafer shaped form factors depending on the device, including 150mm, 200mm and 300mm wafer sizes. The ReticleSense measurement portfolio including the Airborne Particle Sensor (APSR & APSRQ) and next-generation APS2, the Auto Leveling System (ALSR) and the new Auto Multi Sensor (AMSR) are available in a reticle shaped form factor.

For more information about the entire line of CyberOptics solutions please visit the company's website at [www.cyberoptics.com](http://www.cyberoptics.com).

**[About CyberOptics](#)**

CyberOptics Corporation (NASDAQ: CYBE) is a leading global developer and manufacturer of high precision sensing technology solutions. CyberOptics sensors are being used in general purpose metrology and 3D scanning, surface mount technology (SMT) and semiconductor markets to significantly improve yields and productivity. By leveraging its leading edge technologies, the company has strategically established itself as a global leader in high precision 3D sensors, allowing CyberOptics to further increase its penetration of its key vertical segments. Headquartered in Minneapolis, Minnesota, CyberOptics conducts worldwide operations through its facilities in North America, Asia and Europe.

Statements regarding the Company's anticipated performance are forward-looking and therefore involve risks and uncertainties, including but not limited to: market conditions in the global SMT and semiconductor capital equipment industries; increasing price competition and price pressure on our product sales, particularly our SMT systems; the level of orders from our OEM customers; the availability of parts required to meet customer orders; unanticipated product development challenges; the effect of world events on our sales, the majority of which are from foreign customers; rapid changes in technology in the electronics markets; product introductions and pricing by our competitors; the success of our 3D technology initiatives; expectations regarding our 2014 acquisition of Laser Design, Inc. (LDI) and its impact on our operations; and other factors set forth in the Company's filings with the Securities and Exchange Commission.

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